

An Introduction to Atomic Layer Deposition with Thermal Applications

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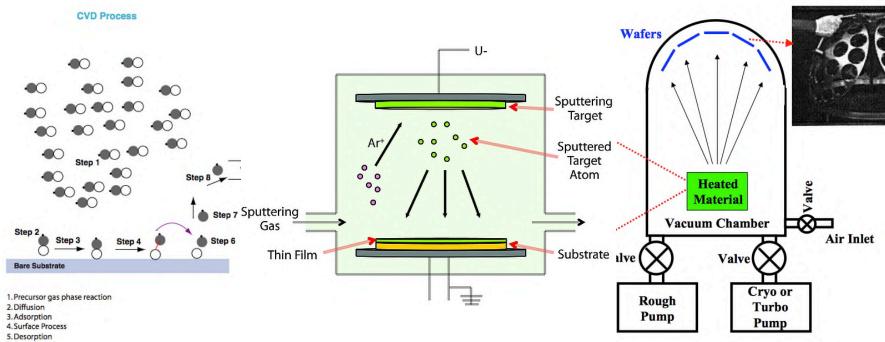


Thin film: thickness typically <1000nm.

Special properties of thin films: different from bulk materials, it may be –

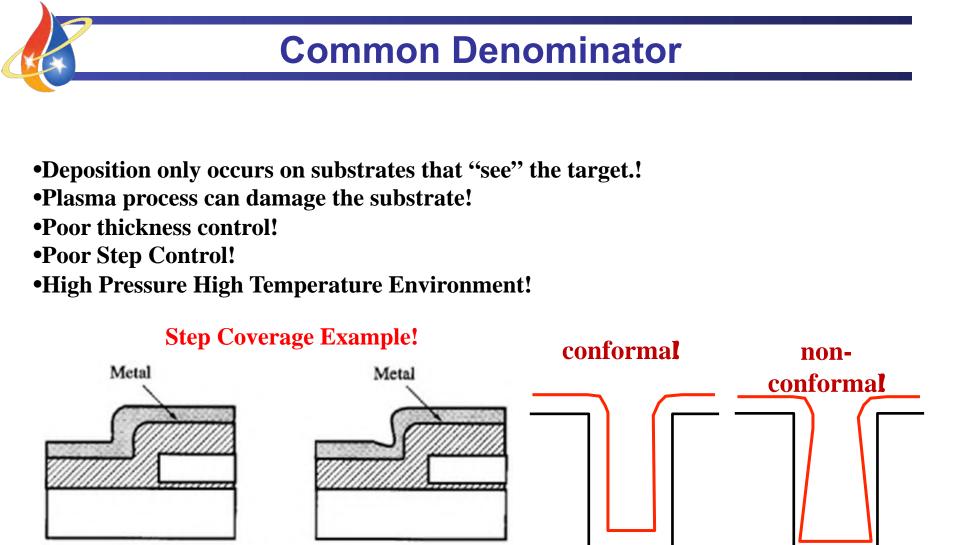
- Not fully dense
- Under stress
- Different defect structures from bulk
- Quasi two dimensional (very thin films)
- Strongly influenced by surface and interface effects

Other Deposition Techniques



6. Diffusion

7. Purge



(a) (b)

Step coverage of metal over non-planar topography.!

(a) Conformal step coverage, with constant thickness on horizontal and vertical surfaces.!

(b) Poor step coverage, here thinner for vertical surfaces.!

Introduction

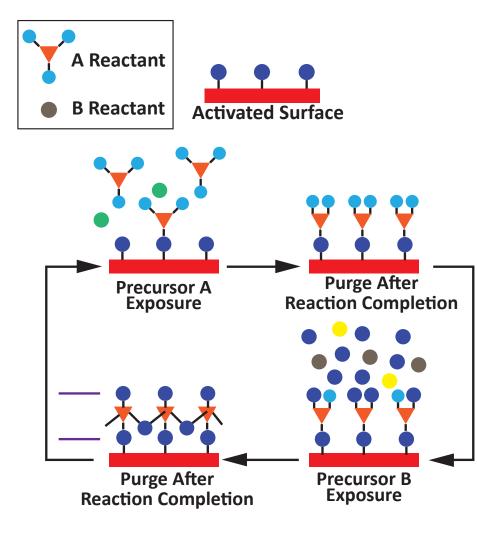
Atomic Layer Deposition

A thin film"nanomanufacturing" tool that allows for the conformal coating materials on a myriad of surfaces with precise atomic thickness control.

Based on:

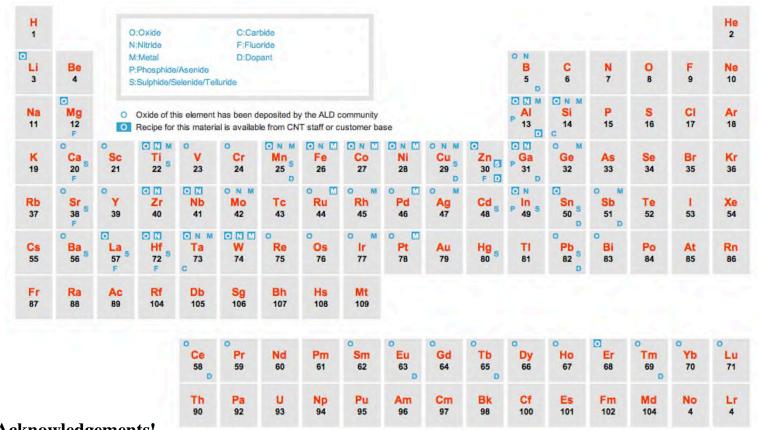
- Paired gas surface reaction chemistries!
- Benign non-destructive temperature and pressure environment
 - Room temperature -> 250 °C (even lower around 45 °C)!
 - Vacuum

ALD Procedure



- A or B exposure = Half Cycle!
- A+B = Full Cycle = 1 Monolayer!
- Digital Process: ABABABAB!
- Not Line of Sight, EVERYTHING GETS COATED!
- Substrate Independent

Periodic Table of ALD Films



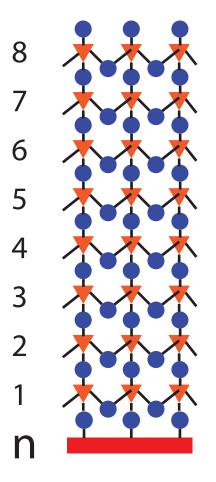
Acknowledgements!

• Gordon, Roy (2008). Atomic Layer Deposition (ALD): An Enable for Nanoscience and Nanotechnology. ! PowerPoint lecture presented at Harvard University, Cambridge, MA.!

• Elam, Jeffrey (2007). ALD Thin Film Materials. Argonne National Laboratory!

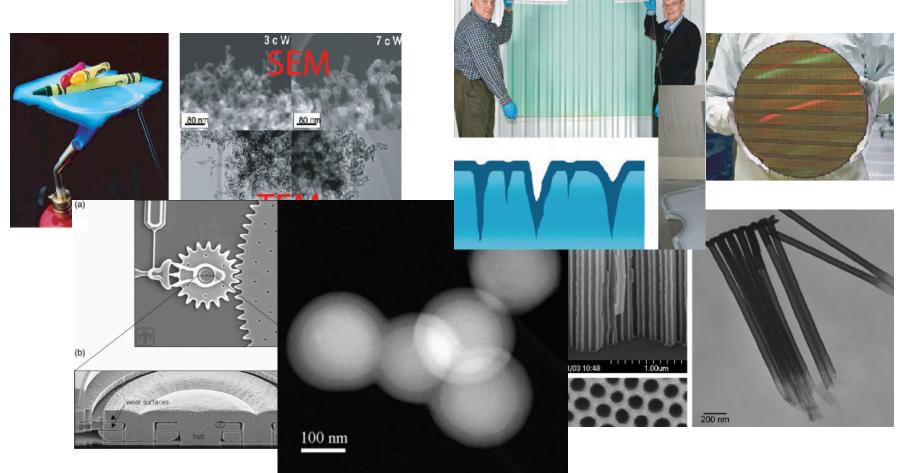
Advantageous Property

Precise Thickness Control Thickness = F (# monolayers) Example: If 1 monolayer = 1 A # monolayers = 7 Thickness = 7 A Reproducibility



Advantageous Property

Substrate Independence



Advantageous Property

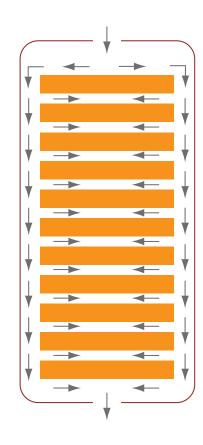
Epitaxial Growth

Batch Process

Artificial trench filled with an ALD nanolaminate Image courtesy of Aalto University (FI)

> Multilayer consisting of: Al2O3 - 25 nm TiN - 20 nm Al2O3 - 25 nm Dr. Fred Roozeboom, NXP Semiconductors Research and Dr. Erwin Kessels, University of Technology, Eindhoventd

> > Coating Silver with Aluminum Oxide *http://www.glassonweb.com/*



Schematic of a 3D battery integrated in a Si-substrate. The cross-section shows the various functional layers in the battery stack as well as the candidate materials. *Knoops, H.C.M. et al., ECS Trans., 25 (2009) pp. 333-344*

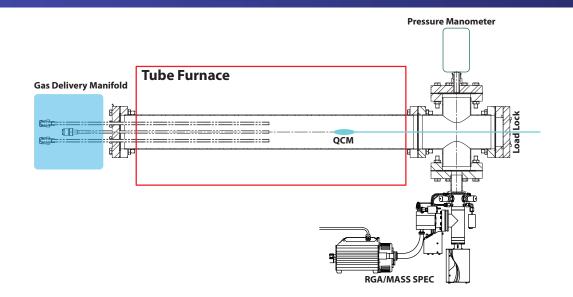
Building off a Commercial Reactor

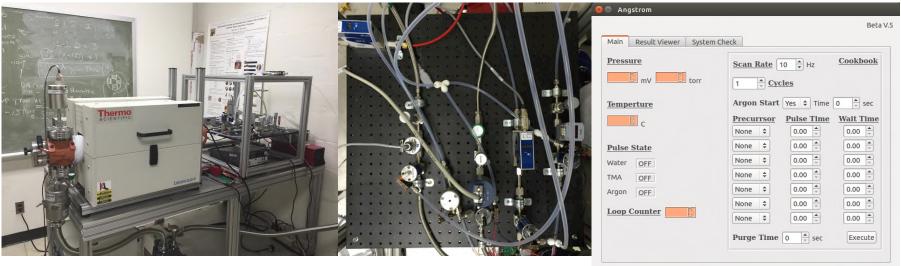
Commercial Options



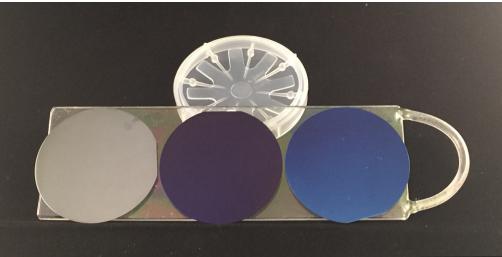


In-House Experimental ALD System





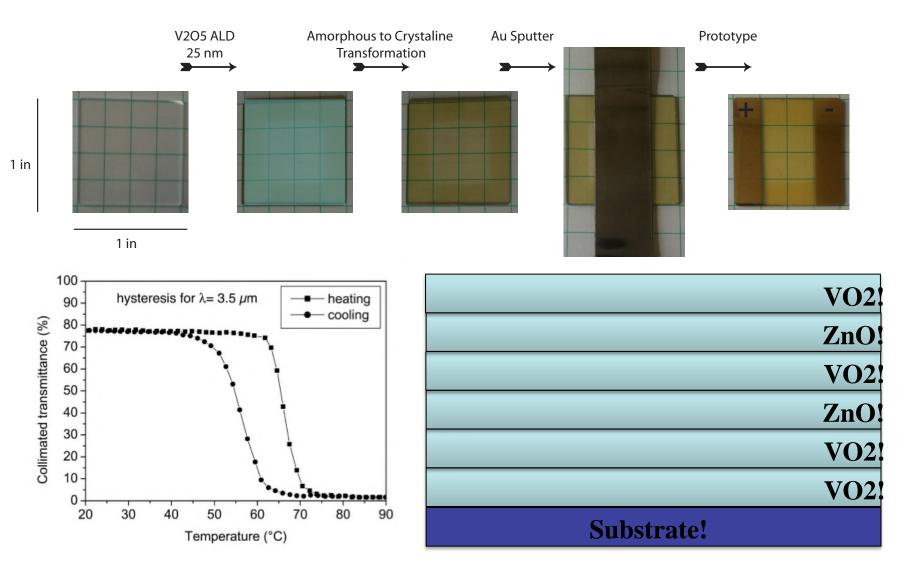
Thermal Applications and Results





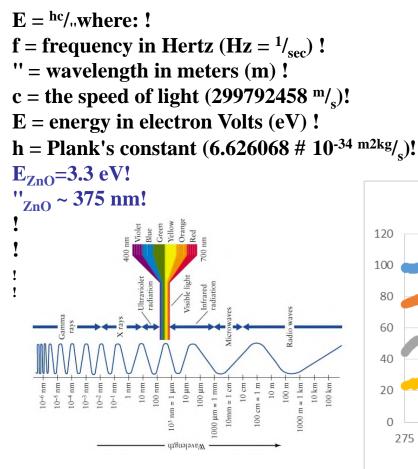
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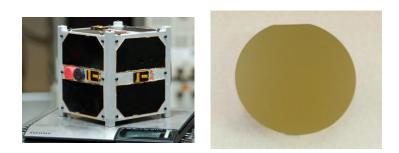
Passive Thermal Films

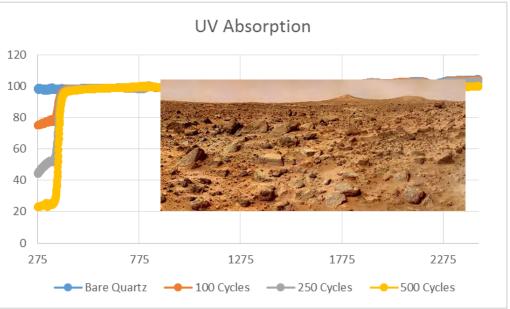


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ZnO

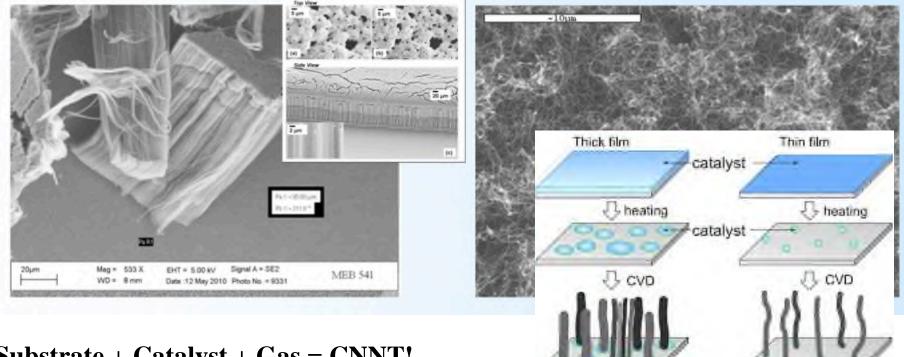






Blacker Than Black Carbon Nanotubes

Fe ALD on Complex Geometries for Carbon Nanotube Growth



Substrate + Catalyst + Gas = CNNT! Si,Ti, flat, 3d + Iron + Ethylene! ! Blacker than NASA Z306 Paint 10X Darker!

Atomic Oxygen Protection



100 nm on Kapton! 1000 Cycles! 155 °C! Al₂O_{3!}

GPM Funded an experiment! at Glenn to determine AO effects! on materials.! !

99% mass retention after a simulated!5 year flux!

Questions?



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